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Supplemental material

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Microelectromechanical system-based condensation particle counter for real-time monitoring of airborne ultrafine particles

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[Channel geometry information]

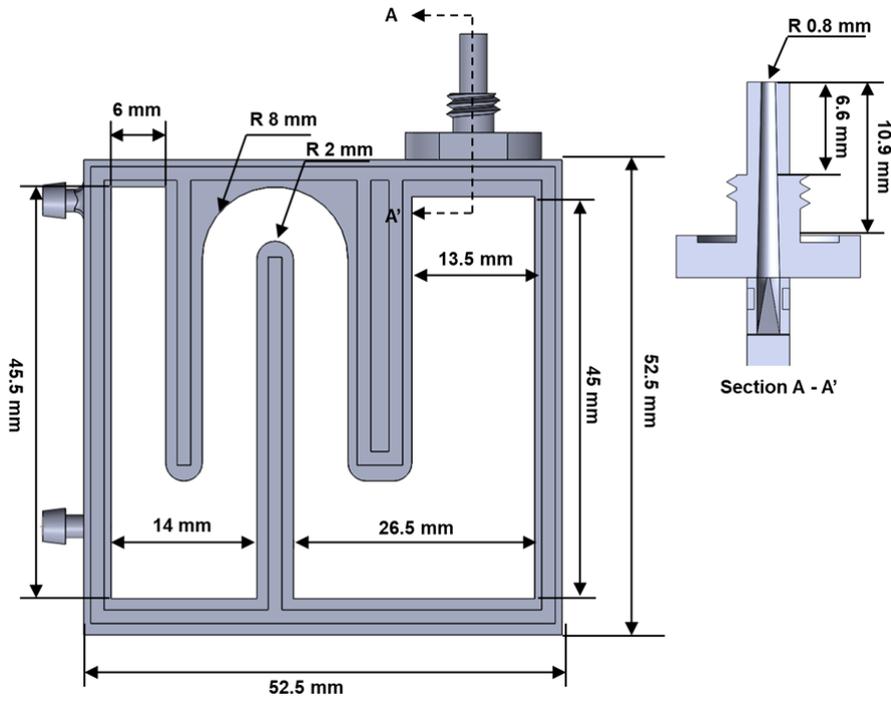


Figure S1 The geometry parameters of the MEMS-based condensation chip.

[Component and price information of the MEMS based CPC]

Components	Used material	Manufacturer	Retail price	Used quantity	Price (\$)	
3D printed channel	SLA (Stereolithography Apparatus)	3D MON, KR	10 \$ / EA	1	10	
Glass	Sodalime glass	SEMISTORE, KR	3 \$ / EA	2 EA	6	
Integrated glass slide	electrodes	AZ GXR-601 Photoresist	Microchem, USA	420 \$ / 3.8 L	5 ml	0.55
		MIF-300 developer	Microchem, USA	170 \$ / 20 L	200 ml	1.7
Micropillar wick		SU-8 2100 photoresist	Microchem, USA	840 \$ / 500 ml	5 ml	8.4
		SU-8 developer	Microchem, USA	336 \$ / 3.8 L	100 ml	8.8

Table S1 Material used for manufacturing a single MEMS-based particle growth system.